

IN THE CLAIMS:

Please cancel claims 21 to 27, without prejudice, and please add new claims 28 to 36 as follows:

28. (New) An inspecting apparatus comprising:

10 a main body;

15 a substrate holder which is arranged horizontally above an upper surface of the main body and which holds a substrate to be inspected;

a pair of guide rails arranged on the main body along respective sides of the substrate holder in an opposing manner;

20 an observation unit supporting section comprising a pair of support columns respectively traveling along the guide rails and a horizontal arm section connecting the support columns;

a micro inspection unit which is movable along the horizontal arm section in a direction perpendicular to the guide rails, and which includes an objective lens for microscopically observing a surface of the substrate to be inspected;

25 a storage section which stores position coordinates of at least one defect on the substrate to be inspected; and

a control section which controls movement of the observation unit supporting section and the micro inspection unit so that an observation optical axis of the objective lens of the micro inspection unit is adjusted to the defect on the substrate to be inspected based on the position coordinates of the defect read from the storage section.

29. (New) The inspecting apparatus according to claim 28,
wherein the guide rails have extensions situated behind a rear
end of the substrate holder and the control section controls
movement of the observation unit supporting section so that the
observation unit supporting section is retreated in the
extensions of the guide rails, when the substrate to be inspected
is supplied to the substrate holder.

30. (New) The inspecting apparatus according to claim 28,
wherein the observation unit supporting section is integrally
provided with a transmission light source arranged under the
substrate holder so as to face a track of movement of the micro
inspection unit.

31. (New) The inspecting apparatus according to claim 30,
wherein the transmission light source comprises a linear light
source which linearly illuminates the substrate to be inspected.

32. (New) The inspecting apparatus according to claim 30,
wherein the transmission light source includes:

a light source which supplies illumination light;

a glass rod which transmits the illumination light

therethrough; and

white stripes applied on a rear portion of the glass rod to
disperse the illumination light transmitted through the glass rod
toward the objective lens of the micro inspection unit.

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33. (New) The inspecting apparatus according to claim 28,
wherein:

the micro inspection unit includes a TV camera which picks
up an image of the surface of the substrate to be inspected taken
5 through the objective lens; and

the control section displays the image picked up by the TV
camera on a TV monitor.

34. (New) The inspecting apparatus according to claim 28,
wherein the micro inspection unit includes an ocular lens for
observing an image of the surface of the substrate to be
inspected taken through the objective lens.

35. (New) The inspecting apparatus according to claim 28,
wherein:

the micro inspection unit includes a reference light source
which is separated by a predetermined distance from the
5 observation optical axis of the objective lens and which projects
a spot light to designate a position of the defect on the
substrate to be inspected;

the observation unit supporting section and the micro
inspection unit include coordinate scales which detect
10 coordinates of positions thereof, respectively;

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the storage section stores coordinate data from the respective coordinate scales of the observation unit supporting section and the micro inspection unit; and

15 the control section obtains the position coordinates of the defect from the coordinate data of the respective coordinate scales read from the storage section, and controls movement of the observation unit supporting section and the micro inspection unit so that the observation optical axis of the objective lens of the micro inspection unit is adjusted to the defect on the
20 substrate to be inspected based on the coordinate data and the predetermined distance.

36. (New) The inspecting apparatus according to claim 35, further comprising a partial illumination macro light source which is movable along the horizontal arm section in the direction perpendicular to the guide rails, and which partially
5 and macroscopically illuminates the surface of the substrate to be inspected; and

wherein the control section controls movement of the observation unit supporting section and the partial illumination macro light source in X and Y directions and causes the partial
10 illumination macro light source to perform raster scanning of the surface of the substrate to be inspected.